U.S. Patent and Trademark Office PTOL-37 (Rev. 1-04) Examiner Art Unit 1756 Art Unit: 1756

DETAILED ACTION

Response to Amendment

Applicant's request for reconsideration of the finality of the rejection of the last Office action is persuasive and, therefore, the finality of that action is withdrawn.

All previous rejections and objections presented in that Office action are now withdrawn in view of Applicant's current amendments and accompanying remarks filed on 13 April 2004.

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for the following examiner's amendment was given in a telephone interview with Gregory Sebald on 22 April 2004.

The application has been amended as follows:

IN THE SPECIFICATION:

(A) Page 3 line 2, change "step" to --steps--

Page 3 line 6, change "not darkened" to -- are not darkened--

Page 7 line 15, change "containing a" to --containing--

Page 8 lines 20-21, change "allows to obtain" to --allows obtaining--

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Page 8 line 29, change "permits to control precisely these mechanical" to --permits precise control over these mechanical--

Page 9 lines 21-22, change "permits to precisely control the mechanical" to --permits precise control over the mechanical--

Page 10 line 11, change "step" to --a step--

Page 10 line 13, change "slope with" to --slope having--

Page 10 line 14, change "surface" to --substrate--

- (B) Correct and simplify the title to: METHOD OF FABRICATING A SUSPENDED MICROSTRUCTURE WITH A SLOPED SUPPORT
- (C) Amend the abstract to better represent the invention as now claimed:

Page 17 line 9, change "surface" to --substrate--

Page 17 lines 11-12, change "and (f) removing the second layer to obtain the microstructure with the sloped support" to --(f) (i) depositing a fifth planarization layer, (ii) depositing a sixth layer, and (iii) etching the sixth layer; and (g) removing the second layer and the fifth layer to obtain the suspended microstructure with the sloped support--

IN THE CLAIMS:

Claim 6 line 1, change "step (f)" to --the second layer in step (g)--

Claim 7 line 1, change "removal" to --removing--

Claim 7 line 2, change "layer is performed" to --layer in step (g) is performed--

Claim 11 line 1, change "depositing step (ii)" to --depositing of step (ii)--

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Allowable Subject Matter

Claims 1-3 and 5-18 are now allowed.

The following is an examiner's statement of reasons for allowance: the additional limitations of (1) depositing a 5th planarization layer to leave the top portion of the sloped support uncovered, (2) then depositing and etching a 6th layer to form a microplatform followed by (3) subsequent removal of the 2nd temporary and 5th planarization layers to form a suspended microplatform are considered to be allowable over the prior art of record. This is because Burns does not specifically teach using separate temporary and planarization layers on either side of a sloped support before deposition and etching of a microplatform on the sloped support, then subsequent removal of the temporary and planarization layers to form a suspended microplatform, as shown in instant Figures 10E-10G.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to John Ruggles whose telephone number is 571-272-1390. The examiner can normally be reached on Monday-Thursday and alternate Fridays.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Mark Huff can be reached on 571-272-1385. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

John Ruggles

Examiner
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